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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/646,011	08/22/2003	Matthew Weldon	004.0025D1 8969	
29906	7590 01/21/2005		EXAM	INER
INGRASSIA FISHER & LORENZ, P.C.			ROSE, ROBERT A	
7150 E. CAMELBACK, STE. 325 SCOTTSDALE, AZ 85251			ART UNIT	PAPER NUMBER
	,		3723	

DATE MAILED: 01/21/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

Snl

	Application No.	Applicant(s)				
Office Action Commence	10/646,011	WELDON ET AL.				
Office Action Summary	Examiner	Art Unit				
	Robert Rose	3723				
The MAILING DATE of this communication app Period for Reply	ears on the cover sheet with the c	orrespondence address				
A SHORTENED STATUTORY PERIOD FOR REPLY THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a reply If NO period for reply is specified above, the maximum statutory period w Failure to reply within the set or extended period for reply will, by statute, Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	6(a). In no event, however, may a reply be timwithin the statutory minimum of thirty (30) days ill apply and will expire SIX (6) MONTHS from cause the application to become ABANDONE	nely filed s will be considered timely. the mailing date of this communication. O (35 U.S.C. § 133).				
Status						
1) Responsive to communication(s) filed on 22 Au	aust 2003.					
	action is non-final.					
3) Since this application is in condition for allowan						
closed in accordance with the practice under E.	closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.					
Disposition of Claims						
4) Claim(s) 14-37 is/are pending in the application						
	4a) Of the above claim(s) is/are withdrawn from consideration.					
5)⊠ Claim(s) <u>20-37</u> is/are allowed.						
6)⊠ Claim(s) <u>14 and 16-19</u> is/are rejected.	·					
7)⊠ Claim(s) <u>15</u> is/are objected to.	['])⊠ Claim(s) <u>15</u> is/are objected to.					
8) Claim(s) are subject to restriction and/or	election requirement.					
Application Papers						
9)☐ The specification is objected to by the Examiner						
· · · · · · · · · · · · · · · · · · ·	0)☐ The drawing(s) filed on is/are: a)☐ accepted or b)☐ objected to by the Examiner.					
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).						
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).						
11) The oath or declaration is objected to by the Exa	aminer. Note the attached Office	Action or form PTO-152.				
Priority under 35 U.S.C. § 119						
<u> </u>		(d) an (f)				
12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).						
 a) All b) Some * c) None of: 1. Certified copies of the priority documents have been received. 2. Certified copies of the priority documents have been received in Application No 						
					3. Copies of the certified copies of the priority documents have been received in this National Stage	
application from the International Bureau		a in this National Stage				
* See the attached detailed Office action for a list of	• • • • • • • • • • • • • • • • • • • •	d.				
	,					
Attachment(s)	·					
1) Motice of References Cited (PTO-892) Description Notice of Draftsperson's Patent Drawing Review (PTO-948)	4) Interview Summary (PTO-413) Paper No(s)/Mail Date					
induce of Dransperson's Patent Drawing Review (PTO-948) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08)		atent Application (PTO-152)				
Paper No(s)/Mail Date	6) Other:					

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DETAILED ACTION

Receipt is acknowledged of Applicant's Preliminary Amendment, filed August 22,
 2003.

- 2. Claims 1-13 have been canceled.
- 3. Claims 14-37 are presented for examination.
- 4. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 5. Claims 14, and 16-19 are rejected under 35 U.S.C. 103(a) as being unpatentable over Bibby Jr. et al (US 6106662) in view of Sandhu et al (US 5700180). Bibby, Jr. et al disclose a polishing apparatus comprising substantially all of the subject matter set forth in applicant's claims above. Plural fiber optic cables are embedded in the polishing surface to direct light to the surface and measure the reflected light. Note column 7, lines 21-37 wherein an embodiment employing plural sensors in the pad backer is disclosed. The entire surface of the wafer may be monitored if desired(column A spectrometer is used to analyze the reflected light signal, and a controller processes the signal to determine when an endpoint for polishing is achieved. While the device of Bibby, Jr. et al is configured for endpoint detection, it is known to use optical sensing means in the polishing pad to alter at least one parameter of polishing, as taught by Sandhu et al('180). Sandhu et al('180) teach optical measuring of a wafer surface to control various parameters of the polishing process. To utilize a controller in the device

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of Bibby, Jr. et al, which uses the information obtained from the optical sensors, to alter at least one of the parameters of the planarization process would have been obvious in view of Sandhu et al('180). While Bibby, Jr. et al show a single annular band in figure 4, they disclose at column 7, lines 21-37 an embodiment employing plural sensors in the pad backer, and further disclose locating the sensors to monitor the entire surface of the wafer, if so desired. Such configuration would inherently require that the sensors be positioned radially with respect to the wafer. For overlap of the annular bands it is only necessary that the sensors be spaced from each other a distance less than the orbital radius of the pad. This is regarded as merely an obvious matter of design choice within the skill level of those of ordinary skill in the wafer polishing art.

- 6. Claims 15 is objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.
- 7. Claims 20-37 are allowed.
- 8. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure. Kobayashi, et al is cited to show a method of fabricating a semiconductor integrated circuit wherein the surface of the wafer is scanned optically to determine the endpoint based upon the surface appearance as measured by the intensity of light reflected from the surface. Lustig et al(US 5433651) is cited of interest to show measurement of reflected light from the wafer surface during polishing to determine an endpoint. Hiyama et al, and Moriyama et al are cited to show other optical

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measuring techniques for wafer endpoint utilizing reflected light from the wafer surface directed through the pad.

9. Any inquiry concerning this communication should be directed to Robert Rose at telephone number (571) 272-4494.

Robert Rose Primary Examiner Art Unit 3723

Rr

January 10, 2005.